

What is claimed is:

1. A method for forming a thin film pattern by ejecting a liquid drop which is made from a liquid which contains conductive particles to a predetermined thin film forming area on a substrate comprising a step for performing a surface treatment on the substrate before ejecting the liquid drop in which a contact angle of the liquid drop on the substrate is set.
2. A method for forming a thin film pattern according to Claim 1 wherein the contact angle is set according to a diameter of the ejected liquid drop on the substrate.
3. A method for forming a thin film pattern according to Claim 1 or 2 wherein the contact angle is in a range of 15° to 45°.
4. A method for forming a thin film pattern according to Claim 1 further comprising a step for converting the liquid which is ejected on the substrate to a conductive thin film by a thermal treatment or an optical treatment.
5. A thin film manufacturing device which is provided with a liquid drop ejecting device for ejecting a liquid drop to a substrate and a surface treatment device for performing a surface treatment for a surface of the substrate wherein the device for performing a surface treatment performs a surface treatment such that a contact angle of the liquid drops which are ejected from the liquid drop ejecting device is in a predetermined range.
6. A thin film manufacturing device according to Claim 5 wherein the surface treatment is performed such that the contact angle is in a range of 15° to 45°.

7. A conductive thin film wiring which is manufactured according to a method for forming a thin film pattern according to Claim 1.
8. An electro-optic device which is provided with a conductive thin film wiring according to claim 7.
9. An electronic apparatus which is provided with the electro-optic device according to Claim 8.
10. A non-contact card medium which is provided with the conductive thin film wiring according to Claim 9 for an antenna circuit.
11. A thin film transistor which is manufactured according to the method for forming a thin film pattern according to Claim 1.
12. An electro-optic device which is provided with the thin film transistor according to Claim 11.
13. A method of forming a thin film pattern on a substrate having a major surface, said method comprising:
 - pre-treating the surface of the substrate; and
 - ejecting a plurality of conductive droplets onto the surface of the substrate at a contact angle of between about 15 to 45 degrees.

14. The method of claim 13 which further comprises:
 - determining the diameter of the droplets; and
 - selecting the contact angle as a function of the diameter of the droplets.
15. The method of claim 13 wherein the pre-treating of the substrate includes a volatizing treatment followed by a lyophilic treatment.